

PROCEEDINGS OF SPIE

# ***Applied Optical Metrology IV***

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**1–5 August 2021**  
**San Diego, California, United States**

*Sponsored and Published by*  
SPIE

**Volume 11817**

Proceedings of SPIE 0277-786X, V. 11817

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Applied Optical Metrology IV, edited by Erik Novak, James D. Trolinger,  
Christopher C. Wilcox, Proc. of SPIE Vol. 11817, 1181701 · © 2021  
SPIE · CCC code: 0277-786X/21/\$21 · doi: 10.1117/12.2606242

Proc. of SPIE Vol. 11817 1181701-1

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Author(s), "Title of Paper," in *Applied Optical Metrology IV*, edited by Erik Novak, James D. Trolinger, Christopher C. Wilcox, Proc. of SPIE 11817, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X  
ISSN: 1996-756X (electronic)

ISBN: 9781510644724  
ISBN: 9781510644731 (electronic)

Published by  
**SPIE**  
P.O. Box 10, Bellingham, Washington 98227-0010 USA  
Telephone +1 360 676 3290 (Pacific Time)  
[SPIE.org](http://SPIE.org)  
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